



Gases and Facilities Japan Joint TC Chapter

Meeting Summary and Minutes

Japan Fall Meetings 2024

Thursday, October 24, 2024 2:00 PM – 4:40 PM JST

SEMI Japan Office, Tokyo, Japan/ OVTCCM (Hybrid)

TC Chapter Announcements

Next TC Chapter Meeting

Friday, April 25, 2025 2:00 PM – 4:00 PM JST

SEMI Japan Office, Tokyo, Japan/ OVTCCM (Hybrid)

Table 1 Meeting Attendees

Italics indicate virtual participants.

Gases Japan TC Chapter Co-Chairs: Hiromichi Enami (iZOOM), Isao Suzuki (Consultant), Masafumi Kitano (Fujikin)

Facilities Japan TC Chapter Co-Chairs: Hiromichi Enami (iZOOM), Isao Suzuki (Consultant), Masafumi Kitano (Fujikin)

SEMI Staff: Akiko Yoshida (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Consultant	Suzuki	Isao	Tokyo Electron	Hayashi	Haruna
<i>Daido Steel</i>	<i>Sakurai</i>	<i>Takashi</i>	Tokyo Electron	Mashiro	Supika
<i>Iii safety llc</i>	<i>Ko</i>	<i>Kennis</i>	<i>Tokyo Electron</i>	<i>Tomita</i>	<i>Yugo</i>
<i>i-ZOOM</i>	<i>Enami</i>	<i>Hiromichi</i>	<i>SCREEN Semiconductor Solutions</i>	<i>Nishimura</i>	<i>Takayuki</i>
<i>KOKUSAI ELECTRIC</i>	<i>Matsuda</i>	<i>Mitsuhiro</i>	SEMI Japan	Hirabara	Takeaki
Fujikin	Kitano	Masafumi	SEMI Japan	Kamejinaka	Keiko
<i>MARUICHI STAINLESS TUBE</i>	<i>Nagao</i>	<i>Mamoru</i>	SEMI Japan	Kanno	Hirofumi
NISSAN TANAKA	Takamisawa	Kazuhiko	SEMI Japan	Yoshida	Akiko

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
None		

Table 3 TC Chapter Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
None	

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
7205A	Line Item Revision to SEMI F44-0307 (Reapproved 0818), SPECIFICATION FOR MACHINED STAINLESS STEEL WELD FITTINGS	
Line Item 1	Modifications to comply with the Style Manual (Type 2 editorial changes)	Passed as balloted

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
Line Item 2	Modifications to avoid self-contradictory sentences and for more clarification	Passed as balloted
Line Item 3	Deletion of wall thickness of tube end	Passed as balloted
7206	Line Item Revision to SEMI F45-0307 (Reapproved 0818), SPECIFICATION FOR MACHINED STAINLESS STEEL REDUCINGWELD FITTINGS	
Line Item 1	Modifications to comply with the Style Manual (Type 2 editorial changes)	Passed as balloted
Line Item 2	Modifications to avoid self-contradictory sentences and for more clarification	Passed with an editorial change
Line Item 3	Deletion of wall thickness of tube end	Passed as balloted

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Ratification Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>ISC A&R Action</i>	<i>A&R Forms</i>
None			

Note 1: **Passed** Ratification ballots will be submitted to SEMI publication for final processing.

Note 2: **Failed** Ratification ballots were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 6 Activities Approved by the GCS between meetings of the TC Chapter

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
7297	SNARF	E137 Revision TF	Revision to E137-0705 (Reapproved 0118), Guide for Final Assembly, Packaging, Transportation, Unpacking, and Relocation of Semiconductor Manufacturing Equipment - <i>Approved 10/11/2024</i>

Table 7 Authorized Activities

Listing of all revised or new SNARF(s) and TFOF(s) approved by the Originating TC Chapter.

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

Table 8 Authorized Ballots

<i>#</i>	<i>When</i>	<i>TF</i>	<i>Details</i>
7297	Cycle 2, 2025	E137 Revision TF	Revision to E137-0705 (Reapproved 0118), Guide for Final Assembly, Packaging, Transportation, Unpacking, and Relocation of Semiconductor Manufacturing Equipment

Table 9 SNARF(s) Granted a One-Year Extension

<i>#</i>	<i>TF</i>	<i>Title</i>	<i>Expiration Date</i>
None			

Table 10 SNARF(s) Abolished

#	TF	Title
None		

Table 11 Standard(s) to receive Inactive Status

Standard Designation	Title
None	

Table 12 New Action Items

Item #	Assigned to	Details
G+F_20241024-01	SEMI Staff	To submit the results of Doc.#7205A and 7206A ballot review to the ISC A&R for procedural review.
G+F_20241024-02	5-year Review TF	To prepare PCR to make an editorial change to SEMI F44. (Refer to New Business section.)
G+F_20241024-03	E137 Revision TF	To submit Doc.#7292, Revision to E137-0705 (Reapproved 0118), Guide for Final Assembly, Packaging, Transportation, Unpacking, and Relocation of Semiconductor Manufacturing Equipment for Cycle 2, 2025.

Table 13 Previous Meeting Action Items

Item #	Assigned to	Details
G+F_20240126-01	5-year Review Task Force	To submit Doc.#7205A, Line Item Revision to SEMI F44-0307 (Reapproved 0818), Specification for Machined Stainless Steel Weld Fittings for Cycle 4 or 5. →Closed.
G+F_20240126-02	5-year Review Task Force	To submit Doc.#7206A, Line Item Revision to SEMI F45-0307 (Reapproved 0818), Specification for Machined Stainless Steel Reducing Weld Fittings for Cycle 4 or 5. →Closed.

1 Welcome, Reminders, and Introductions

Masafumi Kitano (Fujikin) called the meeting to order at 2:00 PM JST. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01_Required Meeting Elements March 2024_J

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: Approve the minutes as written.

By / 2nd: Takayuki Nishimura (SCREEN Semiconductor Solutions)/ Hiromichi Enami (i-ZOOM)

Discussion: None.

Vote: 6-Y 0-N. Motion passed.

Attachment: 02_G+F Japan TC_Minutes_20240628_R2

3 Liaison Reports

3.1 Japan Regional Standards Committee (JRSC)

Masafumi Kitano (Fujikin) reported for the JRSC that there had been no updates related to Gases and Facilities Japan Joint TC Chapter from the previous meeting.

3.2 Global Coordinating Subcommittee (GCS)

Akiko Yoshida (SEMI Japan) reported for the GCS of the global Facilities TC and global Gases TC that the GCS approved the followings:

- Doc.#6628A, New Standard: Guide for Facilities Data Package for Manufacturing Equipment Installation and Building Information Modeling was authorized to be submitted for Cycle 7 - *Approved 08/28/2024*.
- Doc.#7202B, Line Item Revision to SEMI F69-1213E, Test Method for Transport and Shock Testing of Gas Delivery Systems was authorized to be submitted for Cycle 7 - *Approved 08/31/2024*.
- SNARF#7297, Revision to E137-0705 (Reapproved 0118), Guide for Final Assembly, Packaging, Transportation, Unpacking, and Relocation of Semiconductor Manufacturing Equipment - *Approved 10/11/2024*.

3.3 Gases and Liquid Chemicals Europe Joint TC Chapter

Akiko Yoshida (SEMI Japan) reported for the Gases and Liquid Chemicals Europe Joint TC Chapter that there had been no updates from the previous meeting.

3.4 Facilities and Gases North America Joint TC Chapter

Akiko Yoshida (SEMI Japan) reported for the Facilities and Gases North America Joint TC Chapter. Of note:

- Chair of the Facilities NA TC Chapter will be stepping down.
- Action needed to either send to Inactive Status or issue new SNARF for below standards documents:
 - SEMI E51, Guide for Typical Facilities Services and Termination Matrix
 - SEMI E76, Guide for 300 mm Process Equipment Points of Connection to Facility Services
 - SEMI E6, Guide for Semiconductor Equipment Installation Documentation
- Doc.#6628A, New Standard: Guide for Facilities Data Package for Semiconductor Manufacturing Equipment Installation and Building Information Modeling was submitted for Cycle 7.
- Voltage Sag Immunity Task Force submitted revision SNARF for SEMI F47 to keep from moving to Inactive Status and TF web conferences have been held.
- There are a number of documents under the Gases NA TC Chapter that are subject to a 5-year review but overdue.

Supika Mashiro (Tokyo Electron) raised concern that documents used in the Voltage Sag Immunity TF are shared on the TF leader's company's shared site, and requested that SEMI staff contact the TF leader to use Connect@SEMI site for document depository.

Attachment: 03_NA F&G Liaison Report July2024 v1

3.5 Facilities Korea TC Chapter

Akiko Yoshida (SEMI Japan) reported for the Facilities Korea TC Chapter that there had been no updates from the previous meeting.

4 SEMI Staff Report

Akiko Yoshida (SEMI Japan) gave the SEMI Staff Report. Of note:

- SEMICON West 2024 will be held in Phoenix, Arizona in October. From the following year, the venue of SEMICON West will alternate between Phoenix and San Francisco every October thereafter.
- Accordingly, the timing of NA Standards Meetings next year will be different than in the past.
- TFs have until 02/20/24 to implement use of Connect@SEMI (<https://connect.semi.org>) for TF management and document development depository. Once TFs have implemented use of Connect@SEMI, they shall use it to: maintain the TF member roster up to date, share the working drafts in PDF, and distribute the Draft Document at least one week before ballot submission to SEMI. Training materials for TF leaders and members (users) are available on the SEMI website.
- During SEMICON Japan 2024, the first ever global event “Global Standards Summit” will be held on Thursday, December 12 10:30-16:30 at International Conference Center at Tokyo Big Sight. This inaugural Summit aims to identify standards-critical areas and work towards an industry standardization strategy for the next 3- and 7-year time horizons, instead of addressing the current challenges.

Attachment: 04_Staff Report July 2024 v4_ay_R1

5 Ballot Review

NOTE 1: TC Chapter adjudication of ballots is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment file name for each balloted document is provided.

5.1 *Doc.#7205A, Line Item Revision to SEMI F44-0307 (Reapproved 0818), Specification for Machined Stainless Steel Weld Fittings*

- Line Item 1, 2 and 3 **passed** the TC Chapter review as balloted. Refer to attachment below for full details.

5.2 *Doc.#7206A, Line Item Revision to SEMI F45-0307 (Reapproved 0818), Specification for Machined Stainless Steel Reducing Weld Fittings*

- Line Item 1 and 3 **passed** the TC Chapter review as balloted and Line Item 2 **passed** the TC Chapter review with an editorial change. Refer to attachment below for full details.

Attachment: 05_7205A_Ballot Review

06_7206A_Ballot Review

6 Task Force Reports

6.1 *Gases Japan TC Chapter*

6.1.1 *5-year Review Task Force*

Nothing specific to report.

6.2 *Facilities Japan TC Chapter*

6.2.1 *F1 Revision Task Force*

Nothing specific to report.

6.2.2 *E137 Revision Task Force*

Haruna Hayashi (Tokyo Electron) reported for the E137 Revision TF. The kick-off meeting was held on August 23 and have bi-weekly TF meetings. The SNARF was approved by the GCS in October and the TF is now working on



Doc.#7297, Revision to E137-0705 (Reapproved 0118), Guide for Final Assembly, Packaging, Transportation, Unpacking, and Relocation of Semiconductor Manufacturing Equipment. The revision work will include expansion of Scope to include SME and AMHS equipment, update in Terminology section, and addition of optional material as crating/ packaging material other than wood. The TF plans to submit the ballot for Cycle 2, 2025.

Attachment: 07_241024 TF report v2

6.2.3 5-year Review Task Force

Refer to 5. Ballot Review for the details.

7 Old Business

7.1 Project Period Review

No SNARF will be expiring soon.

7.2 5-year Review

No document is subject for 5-year review within this year.

8 New Business

8.1 Issue Raised Outside of Line Item 2 of Doc.#7205A.

Masafumi Kitano (Fujikin) said Line Item 2 of Doc.#7205A passed the TC Chapter review as balloted, however, the 5-year Review TF intends to make editorial change on F44 based on the Comment received from Felix Shestatski from Kamano Engineering. The TF will prepare the Publication Change Request (PCR) by the next TC Chapter meeting to address this issue as an editorial change outside of Letter Ballot.

8.2 TFOF for SEMI E137 Revision Activities

Haruna Hayashi (Tokyo Electron) proposed to submit Doc.#7297, Revision to E137-0705 (Reapproved 0118), Guide for Final Assembly, Packaging, Transportation, Unpacking, and Relocation of Semiconductor Manufacturing Equipment for Cycle 2, 2025.

Motion: Authorize Doc.#7297 for Letter Ballot in Cycle 2, 2025.

By / 2nd: Haruna Hayashi (Tokyo Electron)/ Isao Suzuki (Consultant)

Discussion: None.

Vote: 7-Y 0-N. Motion passed.

9 Action Item Review

9.1 Open Action Items

Item #	Assigned to	Details
G+F_20240628-01	5-year Review Task Force	To submit Doc.#7205A, Line Item Revision to SEMI F44-0307 (Reapproved 0818), Specification for Machined Stainless Steel Weld Fittings for Cycle 6 or later. →Closed
G+F_20240628-02	5-year Review Task Force	To submit Doc.#7206, Line Item Revision to SEMI F45-0307 (Reapproved 0818), Specification for Machined Stainless Steel Reducing Weld Fittings for Cycle 6 or later. →Closed

9.2 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
G+F_20241024-01	SEMI Staff	To submit the results of Doc.#7205A and 7206A ballot review to the ISC A&R for procedural review.
G+F_20241024-02	5-year Review TF	To prepare PCR to make an editorial change to SEMI F44. (Refer to New Business section.)
G+F_20241024-03	E137 Revision TF	To submit Doc.#7292, Revision to E137-0705 (Reapproved 0118), Guide for Final Assembly, Packaging, Transportation, Unpacking, and Relocation of Semiconductor Manufacturing Equipment for Cycle 2, 2025.

10 Next Meeting and Adjournment

The next meeting is scheduled for Friday, April 25, 2025 2:00 PM – 4:00 PM at SEMI Japan, Tokyo, Japan and via OVTCCM. See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: [4:40 PM JST].

Respectfully submitted by:

Akiko Yoshida

Standards & EHS

SEMI Japan

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Minutes tentatively approved by:

Hironichi Enami (iZoom) , Co-chair	November 2, 2024
Isao Suzuki (Consultant), Co-chair	October 31, 2024
Masafumi Kitano (Fujikin), Co-chair	November 1, 2024

Table 14 Index of Available Attachments^{#1}

<i>Title</i>	<i>Title</i>
01_Required Meeting Elements March 2024_J	05_7205A_Ballot Review
02_G+F Japan TC_Minutes_20240628_R2	06_7206A_Ballot Review
03_NA F&G Liaison Report July2024 v1	07_241024 TF report v2
04_Staff Report July 2024 v4_ay_R1	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Akiko Yoshida at the contact information above.